





Sheet 1 of 1

Form PTO-1449  
(Rev. 8-83)U.S. Department of Commerce  
Patent and Trademark Office

Atty. Docket No. 0756-945

Serial No. 08/169,127

## INFORMATION DISCLOSURE STATEMENT

(Use several sheets if necessary)

Applicant Hisato SHINOHARA et al.

Filing Date December 20, 1993

Group 1586

## U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date (if appropriate)
<i>MSH</i>	4 1 8 1 5 6 3	1980 <i>Jun</i>	Miyaka et al.	427	53.1	
<i>MSH</i>	4 2 9 2 0 9 2	1981 <i>Sept</i>	Hanak	427	53.1	
<i>MSH</i>	4 4 1 3 0 2 0	1983 <i>Nov</i>	McKee et al.	427	53.1	
<i>MSH</i>	4 6 8 0 8 5 5	1987 <i>July</i>	Yamazaki et al.	156	1643 2 0	
<i>MSH</i>	4 7 1 3 5 1 8	1987 <i>June</i>	Yamazaki et al.	427	53.1	
<i>MSH</i>	4 7 5 3 8 5 5	1988 <i>June</i>	Haluska et al.	427	58	12/4/86
<i>MSH</i>	4 7 5 3 8 5 6	1988 <i>June</i>	Haluska et al.	427	53.1	1/2/87
<i>MSH</i>	4 7 8 6 3 5 8	1988 <i>Nov.</i>	Yamazaki et al.	156	643	8/7/87

## FOREIGN PATENT DOCUMENTS

Document Number	Date	Country	Class	Subclass	Translation Yes No
<del>5 7 7 9 1 4</del>	<del>1982</del>	<del>no such number in previous case</del>			
5 7 1 5 8 6 2 3	1982	Japan			✓
63 1 9 5 1 4 8	1988	Japan			✓

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)


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## U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date (if appropriate)
	3,848,104	11/12/1974	Locke			
	3,877,777	04/15/1975	Glenn, Jr.			
	4,154,530	05/15/1979	Connolly, Jr. et al.			
	4,341,569	07/27/1982	Yaron et al.			
	4,358,659	11/09/1982	Spohnheimer			
	4,370,175	01/25/1983	Levatter			
	4,468,551	08/28/1984	Neiheisel			
	4,543,464	09/24/1985	Takeuchi			
	4,874,920	10/17/1989	Yamazaki et al.			
	4,937,129	06/26/1990	Yamazaki			
	4,970,368	11/13/1990	Yamazaki et al.			
	4,970,369	11/13/1990	Yamazaki et al.			
	5,306,651	04/26/1994	Masumo et al.			
	5,320,984	06/14/1994	Zhang et al.			
	5,432,112	07/11/1995	Hong			
	5,453,858	09/26/1995	Yamazaki			
	5,897,799	04/27/1999	Yamazaki et al.			
	6,002,101	12/14/1999	Yamazaki et al.			
	6,149,988	11/21/2000	Shinohara et al.			

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TC 1700

## FOREIGN PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Country	Class	Subclass	Translation Yes No
	0 322 258	06/28/1989	EP			Full Eng
	01-241862	09/26/1989	JP			Full Eng
	04-338631	11/25/1992	JP			Full Eng
	05-021339	01/29/1993	JP			Full Eng
	55-032026	03/06/1980	JP			Full Eng
	57-079914	05/19/1982	JP			Eng Abst
	60-245124	12/04/1985	JP			Full Eng
	60-257511	12/19/1985	JP			Full Eng
	61-080815	04/24/1986	JP			Full Eng

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Examiner Initial	Document Number	Date	Country	Class	Subclass	Translation Yes No
	61-141174	06/28/1986	JP			Full Eng
	63-025933	02/03/1988	JP			Full Eng
	63-084789	04/15/1988	JP			Eng Abst
	63-195149	08/12/1988	JP			Eng Abst

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

Examiner Initial	
	Grimm, "Optical System for Laser Machining of Narrow Slots", pp. 2641-2642, February 1972, IBM Technical Disclosure Bulletin, Vol. 14, No. 9
	Harvey pp. 10-11, January 1962, Optics: Experiments and Demonstration
	"Excimer Laser Annealing Apparatus Leonix", pp. 196-197 (Translation pages 1-4), October 1992, Semiconductor World
	Kaneko, "Excimer Laser Annealed Poly-Crystalline Silicon TFT", pp. 679-683, January 1990, T. IEEE Japan, Vol. 110-A, No. 10
	Morikawa et al., "Special Article: Present Situation of Laser Processing Technique", pp. 66-68, August 1990, Laser Group, Engineering Section, Mechatronics Apparatus Division, with Full English Translation
	Misura et al., "High-Performance Low-Temperature Poly-Si TFT's for LCD", pp. 436-439, January 1987, IEDM 87
	Fujii et al., "A 10MHz Integrated Driver Circuit for Active-Matrix LCDs Using Laser-Recrystallized Silicon TFT's", pp. 448-451, January 1987, IEDM 87
	Sera et al., "High-Performance TFT's Fabricated by XeCl Excimer Laser Annealing of Hydrogenated Amorphous-Silicon Film", pp. 2868-2872, December 1989, IEEE Transactions on Electron Devcies, Vol. 36, No. 12
	Sameshima et al., "XeCl Excimer Laser Annealing Used to Fabricate Poly-Si TFT's", pp. 1789-1793, October 1989, Japanese Journal of Applied Physics, Vol. 28, No. 10
	McGrath, "Applications of Excimer Lasers in Microelectronics", pp. 165-169, December 1983, Solid State Technology

Examiner

Date Considered

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